

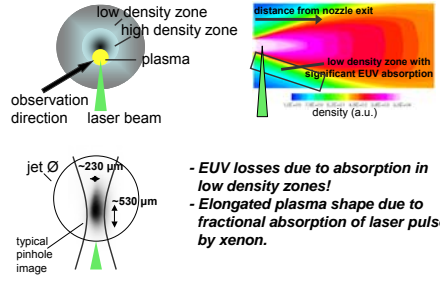


EUV yield enhancement due to propagating shockwaves in laser produced plasmas

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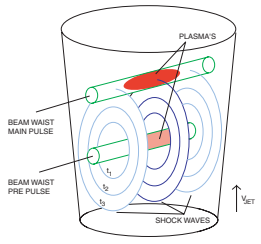
GAZEUS/VAPOUR JETS AS TARGET FOR EUV GENERATION

- Common problem of Xe jets, Sn vapour jets is reduced EUV yield due to increase in density
- Expansion results in low density Xe/Sn volume → major absorption loss, occurring in most EUV sources [1,2]



- EUV losses due to absorption in low density zones!
- Elongated plasma shape due to fractional absorption of laser pulse by xenon.

PRINCIPLE OF THE SHOCK WAVE ENHANCED DENSITY TECHNIQUE

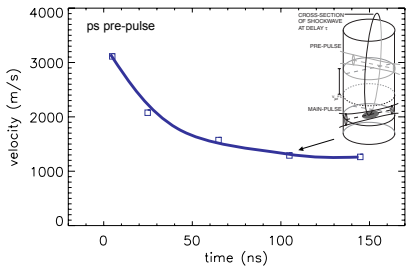


Scouting experiment using ns prepulses:
 1) Apply pre-pulse to produce shock wave, jet density is increased locally!
 2) Produce EUV by main-pulse interaction with shockwave. (fixed delay 7 ns)
 Laser: Nd:YAG, 6 ns, 532 nm, 10¹² W/cm²

SECOND STAGE: EXPERIMENTS USING PS PRE-PULSES AT CCLRC RUTHERFORD APPLETON LABORATORY

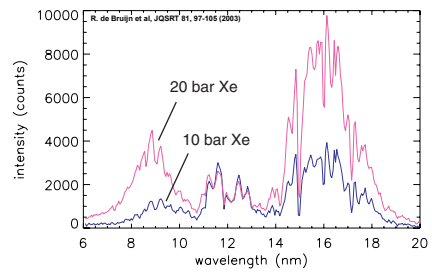
shockwave density ∝ shockwave velocity and shockwave velocity ∝ laser power density/energy
 Increase distinct separation pre- and main-pulse
 No EUV contribution from pre-pulse
 Pre-pulse 4 ps, 248 nm, 4 x 10¹⁴ W/cm²
 Main-pulse 6 ns, 532 nm, 7 x 10¹² W/cm²

MODELING OF SHOCKWAVE PROPAGATION BY EPPRA SAS WITH Z* CODE [3-6]



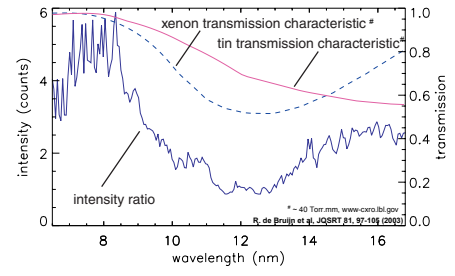
The average shockwave velocity at 150 ns is 1.2 x 10⁴ m/s. From measurements we found 1.0 x 10⁴ m/s → Modeling with Z* code confirms experiment!

CHANGES IN XUV INTENSITY DUE TO HIGHER DENSITY



Standard method, increase of yield by increasing backing pressure does not lead to similar increase between 11-14 nm!

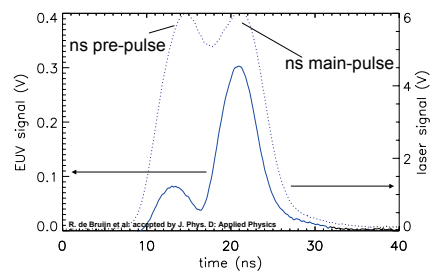
RATIO OF XUV XENON SPECTRA



Low absorption in Xe (< 11, >16 nm) → Intensity ∝ (density)²
 High absorption in Xe (~13.5 nm) → Intensity ≈ constant

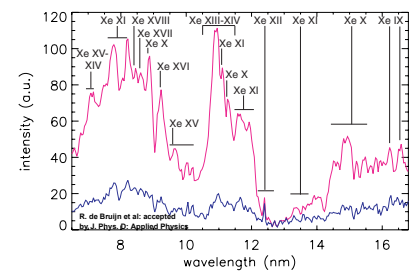
Solutions: replace xenon by EUV transparent buffer gas or increase density inside the jet only!

FIRST STAGE: SCOUTING EXPERIMENT AT FOM NARROW BAND EUV YIELD @ 13.5 nm



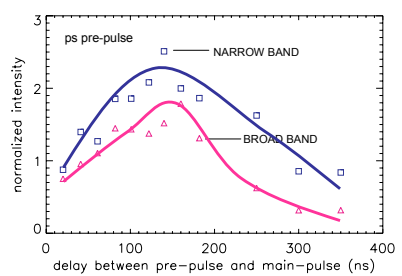
Narrow band EUV yield increase 4 times with respect to use of main pulse only!
 Note: 140 mJ pre-pulse energy used.

CHANGE IN SPECTRAL INTENSITY



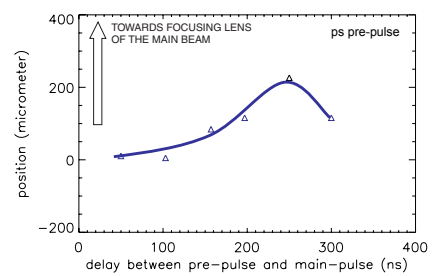
Up to 5 times increase in broad band yield!

NARROW AND BROAD BAND EUV YIELD



- Increase was still 2.5 times!
- Maximum increase at delay of 150-160 ns!
- Note: only 10 mJ pre-pulse energy used.

SHIFT IN PLASMA POSITION



- 1) < 100 ns → increase due to higher density
- 2) 100-200 ns → lower shock wave density BUT decreased EUV absorption results in net gain, due to plasma-edge position.
- 3) > 200 ns → too low target density

SUMMARY

- Laser pulse interaction with shockwaves results in a higher yield without increased EUV absorption. Up to 4 times increase @ 13.5 nm is measured.
- A delay between pre- and main-pulse can be used to control the plasma position, and thus reduce EUV absorption.
- The use of ns pre-pulses results in a higher increase due to higher shockwave density compared to ps pre-pulses. This is explained by on going heating of pre-pulse during main-pulse interaction.

OUTLOOK

- Laser pulse interaction with oppositely moving shockwaves like in ICF.
- Use of new beam waist geometries.

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